



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Yasushi OKUBO et al.

Group Art Unit: 1756

Application No.: 10/551,136

Filed: September 29, 2005

Docket No.: 125493

For: MASK BLANK, MANUFACTURING METHOD OF MASK BLANK,
MANUFACTURING METHOD OF TRANSFER MASK AND MANUFACTURING
METHOD OF SEMICONDUCTOR DEVICE

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. In accordance with 37 CFR §1.98(a)(2)(ii), copies of any U.S. patents and patent application publications are not attached.
- ☒ 3. An English language Abstract of one or more non-English language reference is attached. See References 3 and 4.
- ☒ 4. Reference 1 corresponds to reference 3.

Respectfully submitted,

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